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Bib Data Sheet

CONFIRMATION NO. 3893

Yoshinobu Kimura, Tokyo, JAPAN; Takahiro Kamo, Mobara, JAPAN; Yoshiyuki Kaneko, Hachioji, JAPAN; **** CONTINUING DATA*** This application is a 371 of PCT/JP00/04141 06/23/2000 **** FOREIGN APPLICATIONS*** JAPAN 11/181559 06/28/1999 Foreign Priority claimed	SERIAL NUMBE 10/019,407	SERIAL NUMBER 10/019,407 FILING OR 371(c) DATE 03/25/2002 RULE		CLASS 438		GROUP ART UNIT 2813		ATTORNEY DOCKET NO. 520.41003 X00			
Foreign Priority claimed 35 USC 119 (a-d) conditions yes no Met after COUNTRY met Verified and Acknowledged Allowance Examiner's Signature Initials FILING FEE RECEIVED 1524 FEES: Authority has been given in Paper RECEIVED 1524 FILING FEE RECEIVED 1524 FEES: Authority has been given in Paper No to charge/credit DEPOSIT ACCOUNT No for following: STATE OR COUNTRY DRAWING 16 SHEETS DRAWING 16 SHEETS DRAWING 16 SHEETS DRAWING 16 All Fees 1 1.16 Fees (Filing) 1.17 Fees (Processing Ext. of time) 1.18 Fees (Issue) Other Other Other	Takahiro Kamo, Mobara, JAPAN; Yoshiyuki Kaneko, Hachioji, JAPAN; ** CONTINUING DATA *********************** This application is a 371 of PCT/JP00/04141 06/23/2000 ** FOREIGN APPLICATIONS ************************************										
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